



862.C2032

PATENT APPLICATION

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:	)	
	:	Examiner: NYA
HIROSHI TSUJI ET AL.	)	
	:	Group Art Unit: 2881
Application No.: 09/691,234	)	
	:	
Filed: October 19, 2000	)	
	:	
For: ELECTRON BEAM	)	
LITHOGRAPHY APPARATUS	:	January 17, 2001

Commissioner for Patents  
Washington, D.C. 20231

TC 2800 MAIL ROOM  
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JAN 19 2001

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SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Sir:

In compliance with the duty of disclosure under 37 C.F.R. § 1.56 and in accordance with the practice under 37 C.F.R. §§ 1.97 and 1.98, the Examiner's attention is directed to the document identified on the enclosed Form PTO-1449. A copy of the document is also enclosed.

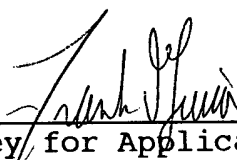
For the concise statement of relevance for the non-English document the Examiner is referred to the abstract attached thereto.

It is respectfully requested that the above information be considered by the Examiner and that a copy of

the enclosed Form PTO-1449 be returned indicating that such information has been considered.

Applicants' undersigned attorney may be reached in our New York office by telephone at (212) 218-2100. All correspondence should continue to be directed to our below listed address.

Respectfully submitted,

  
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Attorney for Applicants

Registration No. 42,476

FITZPATRICK, CELLA, HARPER & SCINTO  
30 Rockefeller Plaza  
New York, New York 10112-3801  
Facsimile: (212) 218-2200  
138452